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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/626,550	07/25/2003	Se-Yeul Bae	009844-0305239	9321	
909 75	90 10/18/2005		EXAM	EXAMINER	
PILLSBURY '	WINTHROP SHAW PI	MALSAWMA, LALRINFAMKIM HMAR			
P.O. BOX 10500 MCLEAN, VA 22102		ART UNIT	PAPER NUMBER		
			2823		
			DATE MAILED: 10/18/2009	5	

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)				
	10/626,550	BAE, SE-YEUL				
Office Action Summary	Examiner	Art Unit				
	Lex Malsawma	2823				
The MAILING DATE of this communication app Period for Reply	ears on the cover sheet with the c	orrespondence address				
A SHORTENED STATUTORY PERIOD FOR REPLY THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply If NO period for reply is specified above, the maximum statutory period we Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	within the statutory minimum of thirty (30) days ill apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONED	ely filed will be considered timely. the mailing date of this communication. (35 U.S.C. § 133).				
Status						
1) Responsive to communication(s) filed on 28 Ju	ly 2005.					
2a) This action is FINAL . 2b) This						
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is						
closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.						
Disposition of Claims						
4) Claim(s) 1 and 5-8 is/are pending in the application 4a) Of the above claim(s) is/are withdraw 5) □ Claim(s) is/are allowed. 6) □ Claim(s) 1 and 5-8 is/are rejected. 7) □ Claim(s) is/are objected to. 8) □ Claim(s) are subject to restriction and/or	n from consideration.					
Application Papers						
9)☐ The specification is objected to by the Examiner 10)☒ The drawing(s) filed on 25 July 2003 is/are: a)☒ Applicant may not request that any objection to the o Replacement drawing sheet(s) including the correction 11)☐ The oath or declaration is objected to by the Examiner	☑ accepted or b)☐ objected to b drawing(s) be held in abeyance. See on is required if the drawing(s) is object	37 CFR 1.85(a). ected to. See 37 CFR 1.121(d).				
Priority under 35 U.S.C. § 119						
 12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority documents 2. Certified copies of the priority documents 3. Copies of the certified copies of the priority application from the International Bureau * See the attached detailed Office action for a list of 	have been received. have been received in Application ty documents have been received (PCT Rule 17.2(a)).	on No d in this National Stage				
Attachment(s)						
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date	4) Interview Summary (Paper No(s)/Mail Dat 5) Notice of Informal Pa 6) Other:	te				

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DETAILED ACTION

Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- 2. Claims 1 and 5-8 are rejected under 35 U.S.C. 102(b) as being anticipated by **Aoki** (6,387,821).

Regarding claims 1 and 5-8:

Aoki discloses (in Figs. 1-4 and Col. 8, lines 18-65) a method of forming metal wiring in a semiconductor device comprising:

forming a bottom metal pattern 105 on a semiconductor substrate (Col. 8, lines 4-5);

forming a low-temperature oxide (HSQ) an insulating layer 106 on the semiconductor substrate including the bottom metal pattern, wherein the low-temperature oxide (HSQ) is formed at the temperature of 400 °C (Col. 8, lines 26-28) and having a thickness of 1200 nm (12000 angstroms);

forming a first photoresist pattern 107 (Fig. 2a) for forming via hole on the low temperature oxide 106;

forming an unfinished via hole by removing the low temperature oxide selectively for a prescribed thickness using the first photoresist pattern as a mask (Fig. 2b), wherein the unfinished via hole is formed to make the thickness of the insulating layer 106 remaining inside the via hole equal to the thickness of the upper part of the damascene contact (i.e., the thickness

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of remaining insulating layer 106 below the unfinished via in Fig. 3a is equal to the thickness of the upper part of the damascene opening in Fig. 3b), accordingly, the thickness of the low temperature oxide remaining inside the via does not exceed a predetermined thickness of an upper part of a damascene contact (NOTE: a "predetermined thickness" would be any thickness disclosed for the upper part of the damascene contact, therefore, Aoki shows that the "predetermined thickness" of the upper part of the damascene contact is not exceeded by thickness of the low temperature oxide remaining inside the via hole);

removing the first photoresist pattern 107 (Figs. 2a-2b);

forming a second photoresist pattern 108 for forming damascene pattern on the low temperature oxide around the unfinished via hole (Fig. 3a);

forming a damascene pattern by removing the low temperature oxide 106 selectively using the second photoresist pattern as a mask (Fig. 3b),;

removing the second photoresist pattern 108 (Figs. 3a-3b); and

forming a metal-wiring-via-damascene contact 111 by filling metal 111 (copper) in the damascene pattern, wherein the damascene contact is formed by dry deposition (i.e., sputtering) of metal on the insulating layer including the damascene pattern and the planarizing the metal 111 by CMP process (Figs. 4a-4b and Col. 8, lines 58-65).

Therefore, Aoki anticipates these claims.

Remarks

3. Applicant's remarks/arguments have been carefully reviewed and considered, but they are not persuasive for the following reasons. The amendment to claim 1 removes the prior

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limitation requiring the thickness of the low-temperature oxide be specifically less than a thickness of the upper part of the damascene contact; therefore, Aoki anticipates claim 1 (as currently amended) because Aoki discloses/shows (in Figs. 3a-3b) that the thickness of the lowtemperature oxide is equal to a "predetermined thickness" of the upper part, i.e., in claim 1 (as currently amended), the thickness of the low-temperature oxide can now be equal to or less than a predetermined thickness of the upper part, where "a predetermined thickness" is essentially any thickness obtained for the upper part, e.g., once a thickness is obtained for the upper part, one could readily refer to the obtained thickness as "a predetermined thickness" for subsequent batches. Applicant's remarks with respect to obtaining a desired sheet resistance has been noted; however, since the information presented in these remarks was not included in the specification as originally filed, it is not considered to be a critical aspect of the current invention, especially because it seems that the thickness relationship between the remaining portion of the lowtemperature oxide and the upper part is no more than a preferred relationship. For example, note the current specification (page 4, lines 12-15), wherein it is disclosed, "[t]he remaining thickness t of the insulating layer 35 when the unfinished via hole 39 is formed is preferably equal to or smaller than thickness t1 of an upper part of a metal damascene contact 45 shown in Fig. 9", and there is no disclosure indicating the criticality of this thickness relationship, especially in the manner suggested by the remarks. Therefore, all pending claims are currently rejected under 35 USC § 102

Conclusion

4. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, THIS ACTION IS MADE FINAL. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

5. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Lex Malsawma whose telephone number is 571-272-1903. The examiner can normally be reached on Mon. - Thur. (4-12 hours between 5:30AM and 10 PM).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Matthew Smith can be reached on 571-272-1907. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Lex Malsawma Office

October 11, 2005

W. David Coleman Primary Examiner